



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/388,826  
Filing Date ..... September 1, 1999  
Inventor..... Weimin Li et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... E.J. Kielin  
Attorney's Docket No. .... MI22-1208  
Title: Low k Interlevel Dielectric Layer Fabrication Methods

**RESPONSE TO JUNE 11, 2003 OFFICE ACTION**

To: Art Unit 2813  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

From: James E. Lake  
Tel. 509-624-4276; Fax 509-838-3424  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

**Amendments**

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